


PTO-1449 Information Disclosure Citation in an Application		Application No. Unassigned Docket Number 064441.0263		Applicant(s) Pascal Huyghe et al. Group Art Unit Unknown Filing Date June 27, 2003			
U.S. PATENT DOCUMENTS							
		DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
	A.						
	B.						
	C.						
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	F.						
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	H.						
	I.						
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	K.						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
							YES NO
	L.						
	M.						
	N.						
	O.						
	P.						
	Q.						
NON-PATENT DOCUMENTS							
		DOCUMENT (Including Author, Title, Source, and Pertinent Pages)					DATE
MA	R.	Edward Suttle et al.'s "Streamlining the front-end reticle fabrication process by improving mask ordering" at internet address < http://www.micromagazine.com/archive/02/06/suttle.html > and published in June 2002 Issue of Micro Magazine. 10 Pages					June 2002
MA	S.	Brock Hotaling, "MaskPilot Revolutionizes Semiconductor Software," <u>Reticle and Mask Solutions</u> , Vol. I, No. 1, Fall 2002, 4 Pages					Fall 2002
	T.	Photronics, Inc., "Photronics eBeam Phase Masks: Tackling the Challenges of Special Lightwave Applications," <u>Reticle and Mask Solutions</u> , Vol. XIII, No. 1, Spring 2002, 4 Pages					Spring 2002
EXAMINER					DATE CONSIDERED		
					2/24/2006		
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.							